

IFW



PATENT
Customer No. 22,852
Attorney Docket No. 04329.2622

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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|--------------------------|---|---------------------------|
| In re Application of: |) | |
| |) | |
| Gaku MINAMIHABA, et al. |) | Group Art Unit: 2823 |
| |) | |
| Serial No.: 09/932,943 |) | Examiner: Lee, Hsien Ming |
| |) | |
| Filed: August 21, 2001 |) | |
| |) | |
| For: SLURRY FOR CHEMICAL |) | |
| MECHANICAL POLISHING AND |) | |
| METHOD OF MANUFACTURING |) | |
| SEMICONDUCTOR DEVICE |) | |

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REQUEST FOR RECONSIDERATION

In reply to the Office Action of April 20, 2004, with a period for response extending through July 20, 2004, Applicants respectfully request the Examiner's reconsideration in view of the remarks that follow:

Remarks begin on page 2 of this paper.